

Block diagram of the adaptive structure control system

- Transducers : energy-conversion devices
include sensors and actuators
 - sensors : acquire information from the system
 - actuators: output actions into the system
 - smart actuators and sensors : actuators and sensors with the use of smart materials
- Major defects in primary sensors :
 - nonlinearity
 - cross-sensitivity
 - noise
 - parameter drift

Some techniques for compensating the defects:

- linearization processes are realizable with digital electronics
- the material forming the sensor is physically organized to maximize the sensitivity of the device to the target variable and to minimize the response to all other physical variables
- use sensor array approach

e.g. chemiresistors

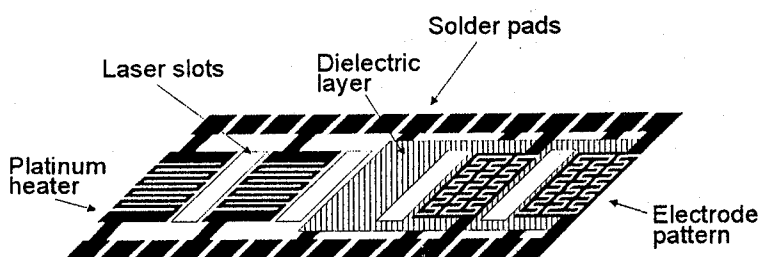


Fig. 7.2. An example of an array of chemiresistors fabricated using thick-film techniques. The slots are cut by a laser and help to isolate each sensor site from its neighbors

- use filters (analog or digital)
- positioning is critical
- the entire compensation and communications system can be constructed in single-chip form
- prefer self-test and auto-calibration features

• Actuators:

- output quantity is an energy or power,
- often in the form of mechanical work
- input of the actuator is driven electrically whenever possible
- connected in series with a power provider (power amplifier)
- considerations:
 - required control authority (amount of control force, moment, strain or displacement, etc.)
 - power consumption, frequency response, and physical constraints such as size and mounting requirements, etc.

• Smart Actuators:

- solid-state actuators: piezoelectric actuators, shape memory actuators, magnetostrictive actuators
- actuators with controllable fluids (smart fluids):
 - magnetorheological fluid actuators,
 - electrorheological fluid actuators

Transduction Devices for Adaptive Structures

- **Accelerometer (sensor)**
 - **Electrodynamic shaker (actuator)**
 - **Electrorheological fluid (actuator)**
 - **Electrostrictive material (actuator)**
 - **Magnetorheological fluid (actuator)**
 - **Magnetostrictive material (actuator)**
 - **Optical fibers (sensor)**
 - **Piezoelectric material (actuator or sensor)**
 - **Shape memory alloy (actuator or sensor)**
 - **Strain gauge (sensor)**
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- Piezoelectric Actuators / Sensors

Constitutive eqs :

$$\begin{cases} D = dT + \epsilon^T E & (1) \\ S = s^E T + d^t E & (2) \end{cases}$$

$$\text{or } \begin{cases} E = -gT + \beta^T D & (3) \\ S = s^D T + g^t D & (4) \end{cases}$$

where g piezoelectric constants

β^T impermeability constants for constant T

s^D elasticity matrix for constant D

From eq (2),

induced strain

$$S_j = d_{ij} E_i$$

(a)

From eq. (1),

when $E = 0$ (short circuit)

$$D_i = d_{ij} T_j$$

(b)

the "strain" constants d

- a measure of the strain produced by an applied electric field (The Motor Effect)
- a measure of the short circuit charge density to the applied stress (The Generator Effect)

From eq (3),

when $D = 0$ (open circuit)

$$E_i = -g_{ij} T_j$$

(c)

the "voltage" constants g

- a measure of the electric field (open circuit) by an applied mechanical stress.

From eq. (4),

$$\text{induced strain} \quad S_j = g_{ij} D_i \quad (d)$$

From (a) - (d),

$$d = \frac{\text{strain developed}}{\text{applied electric field}}$$

$$= \frac{\text{short circuit charge density}}{\text{applied mechanical stress}}$$

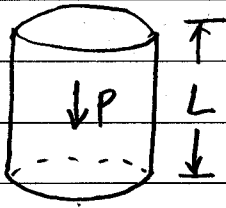
$$g = \frac{\text{open circuit electric field}}{\text{applied mechanical stress}}$$

$$= \frac{\text{strain developed}}{\text{applied charge density}}$$

* Actuators need high "strain" constants d

* Sensors need high "voltage" constants g

e.g.



$$L = 20 \text{ mm}, \quad A = 1 \text{ cm}^2$$

$$g_{33} = 24 \times 10^{-3} \text{ V}\cdot\text{m}/\text{N}$$

$$d_{33} = 390 \times 10^{-12} \text{ m}/\text{V}$$

Voltage - force relationship

$$V = EL \quad \text{and} \quad T = \frac{F}{A}$$

$$E = -g_{33}T \Rightarrow$$

$$V = -g_{33} \frac{L}{A} F$$

$$\text{for } F = -20 \text{ N} \Rightarrow V = 96 \text{ V}$$

Displacement - voltage relation,

$$S = d_{33}E = d_{33} \frac{V}{L} = \frac{\Delta L}{L}$$

$$\Rightarrow \Delta L = d_{33} V$$

$$\text{for } 10 \text{ kV or } E = 500 \text{ V/mm} \Rightarrow \Delta L = 3.9 \mu\text{m}$$